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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 09/360,292
Filing Date July 22, 1999
Inventor Sujit Sharan et al.
Assignee Micron Technology, Inc.
Group Art Unit 1746
Examiner Shamim Ahmed
Attorney's Docket No. M12271106
Title: Plasma Etching Process

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached Form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included herewith. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: July 2, 2003

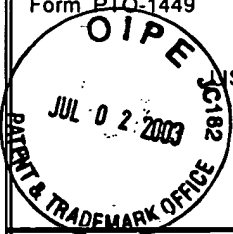
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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1106		SERIAL NO. 09/360,292	
 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Sujit Sharan et al.			
				FILING DATE July 22, 1999		GROUP 1746	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	6,051,503	04-2000	Bhardwaj et al.			
	AB	5,880,005	03-1999	Tsai et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AL						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
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